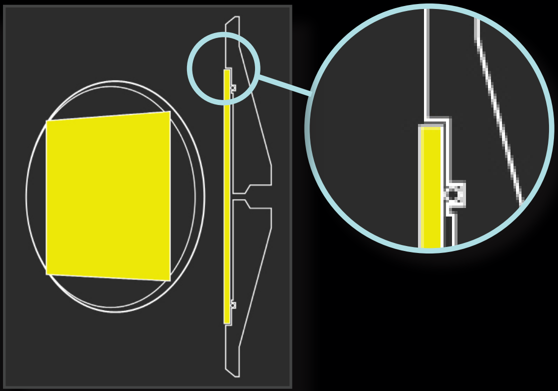
Vacuum Chucks

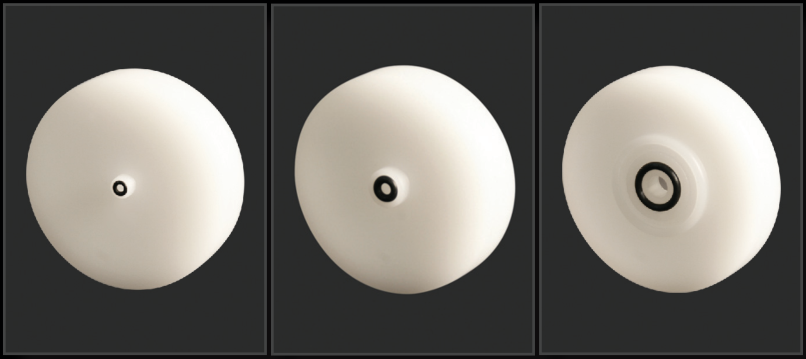


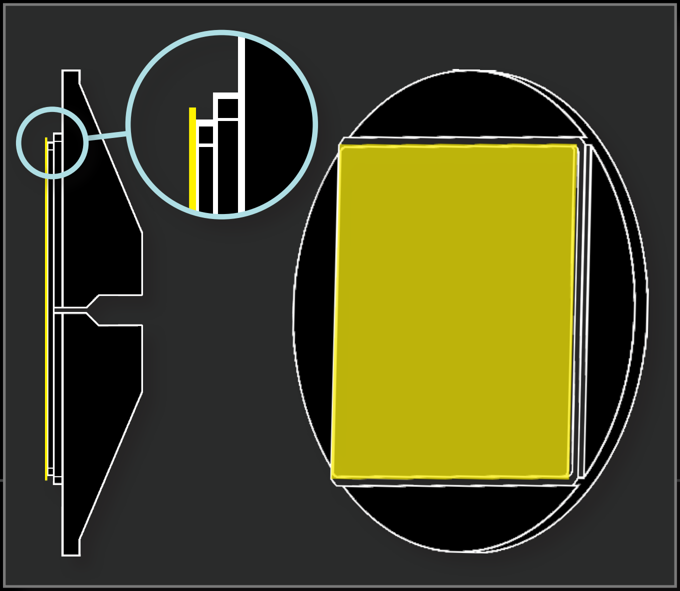
Embedded Vacuum

Vacuum hold, centering and increased uniformity for thick and non-round substrates.

Fragment Adapters

Support small substrates from 3 mm to 45 mm.





High Porosity

A **Laurell Technologies exclusive** design allows our high porosity chucks to hold thin films, fragile substrates, and thermally sensitive materials securely.

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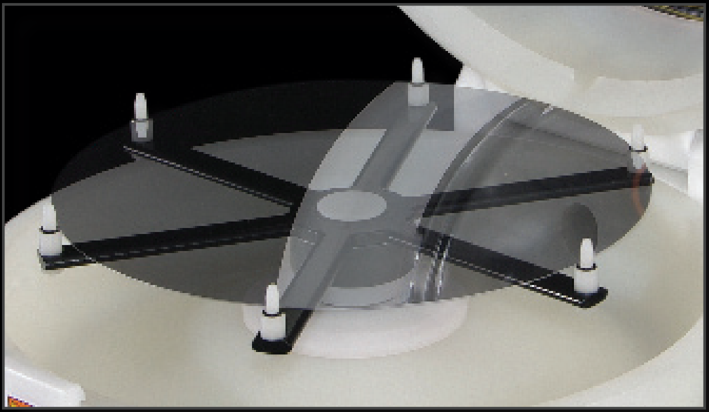
Non-Vacuum Chucks

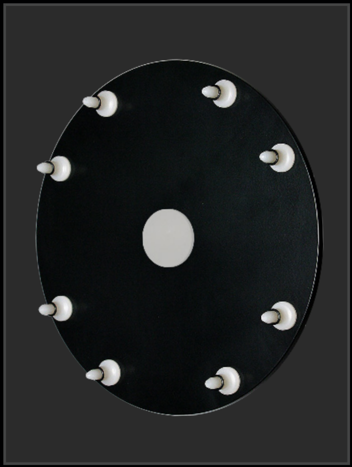


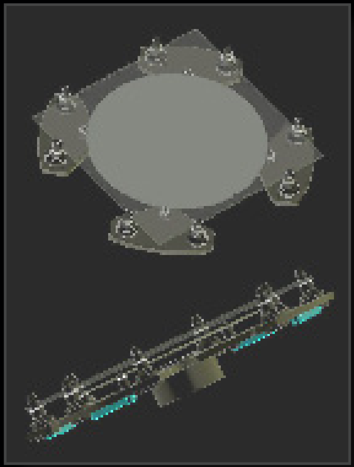
Minimum Contact

Laurell Technologies mechanical pin chucks hold substrates securely, with the smallest possible contact area.

Simultaneous Front & Backside Processing

Open, mechanical chucks allow full access to the substrate for etching, developing, or cleaning.





Special Applications

Do you have a unique substrate you would like to coat, etch, develop, or clean? We have engineered solutions for thousands of customers, let us put our 28 years of experience at your service.

Laurell
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